

Vacuum valve and closure plate for a vacuum valve**Abstract**

The invention relates to a vacuum valve (1) for gas-tight sealing of a flow path (F), comprising at least one thrust rod (7), which has a cylindrical connecting section (10), and a closure plate (11) which is removably mounted on the thrust rod (7) and has at least one concave, semicircular first rod recess (14) corresponding to the connecting section (10). A clamping piece (17), which has a concave, semicircular second rod recess (18) corresponding to the connecting section (10), is adjustably mounted by means of a mechanical fixing element (19) on the closure plate (11) in such a way that the semicircular first rod recess (14) and the opposite semicircular second rod recess (18) define a cylindrical holding region (20) which is adjustable in width and in which the cylindrical connecting section (10) is detachably held. A cavity (21) which extends transversely to the thrust rod axis (8) and in which a resilient pin (22) extends transversely to the thrust rod axis (8) and tangentially to the cylindrical holding region (20) is formed in the first or second rod recess (14; 18), the resilient pin (22) projecting into the cylindrical holding region (20) and being clamped in a joint (16), which extends on the connecting section (10), so that the thrust rod (7) is fixed along the thrust rod axis (8).

Fig. 1